
Process Inventory

Carnegie Mellon's Chemical Hygiene Plan, written by EH&S and approved by department faculty representatives, requires a 'Process Hazard Analysis' for laboratory activities be performed for each research endeavor. As a first step to institute this program we have identified an initial list of Nanofab processes which will require a Process Hazard Analysis. Please check each process that you will perform in the Nanofab. List any additional processes that you will use in the Nanofab in the space provided.

- | | |
|--|---|
| <input type="checkbox"/> Substrate Cleaning | <input type="checkbox"/> Photolithography |
| <input type="checkbox"/> Acid Etching | <input type="checkbox"/> Plasma Etching |
| <input type="checkbox"/> Ion Beam Etching | <input type="checkbox"/> Reactive Ion Etching |
| <input type="checkbox"/> Sputter Deposition | <input type="checkbox"/> Deep Reactive Ion Etching |
| <input type="checkbox"/> Chemical Mechanical Polishing | <input type="checkbox"/> E. Beam Evaporation Deposition |
| <input type="checkbox"/> Rapid Thermal Annealing | <input type="checkbox"/> Thermal Oxidation |
| <input type="checkbox"/> Annealing | <input type="checkbox"/> Electroplating |
| <input type="checkbox"/> SEM Inspection/Sample Prep. | <input type="checkbox"/> Focused Ion Beam Etching |
| <input type="checkbox"/> Optical Inspection | <input type="checkbox"/> Profile Measurement |
| <input type="checkbox"/> Electron Beam Lithography | <input type="checkbox"/> Advanced Oxide Etching |

Others:

Name: _____ Phone: _____ Date: _____



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